

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Intl.
Appl. No. : PCT/JP2003/016441
Applicant : Shigeru UMENO et al.
Intl. Appl.
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PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

February 16, 2005

Sir:

Prior to calculation of the fee and examination on the merits of the above-identified patent application, please amend the application as follows:

U.S. National Stage of
PCT/JP2003/016441
PRELIMINARY AMENDMENT

PATENT

IN THE TITLE:

MANUFACTURING METHOD ~~FOR MANUFACTURING~~ OF SILICON WAFER